

00862.023157



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: Not Yet Assigned
HIROSHI WATANABE ET AL.)	
	:	Group Art Unit: Not Yet Assigned
Application No.: 10/619,576)	
	:	
Filed: July 16, 2003)	
	:	
For: SUBSTRATE PROCESSING)	
METHOD AND SUBSTRATE	:	
PROCESSING APPARATUS)	September 17, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SECOND INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Since the U.S. Patent and Trademark Office waived the requirement under 37 C.F.R. § 1.98 (a)(2)(i) for submitting a copy of each cited U.S. patent and each U.S. patent application publication for all U.S. national patent applications filed after June 30, 2003 and for all international applications that have entered the national stage under 35 U.S.C. § 371 after June 30, 2003, no copies of such documents are enclosed. Copies of the other listed documents are, however, enclosed.

The concise explanation of relevance for the non-English documents may be found, inter alia, in the specification if cited or in the English language abstracts if attached. Also, the concise explanation of relevance for JP 6-326073; JP 62-165939 (JP 7-

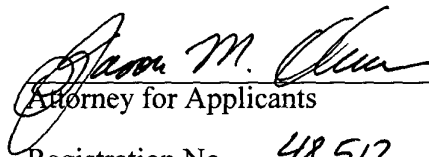
19765 B2); and JP 5-275412 may be found in corresponding U.S. Patent Nos. 5,520,744; 4,746,397; and 5,331,987.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



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FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)				ATTY DOCKET NO. 00862.023,157		APPLICATION NO. 10/619,576	
				APPLICANT Hiroshi Watanabe et al.			
				FILING DATE SEP 16, 2003			
				GROUP N.Y.A.			

U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
	5,520,744	05/28/96	Fujikawa et al.	134	11		
	4,746,397	05/24/88	Maeda et al.	156	637		
	5,331,987	07/26/94	Hayashi et al.	134	102.1		

FOREIGN PATENT DOCUMENTS							
DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT		
JP 3-169013	07/22/91	Japan			Abstract		
JP 5-275412	10/22/93	Japan			Abstract		
JP 6-216101	08/05/94	Japan			Abstract		
JP 6-326073	11/25/94	Japan			Abstract		
JP 7-130699	05/19/95	Japan			Abstract		

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)	
	Takeshi Hattori, <u>Silicon Wafer Surface Cleaning Technique New Edition</u>, pp. 450-463 (2001).

EXAMINER	DATE CONSIDERED
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

